

What is claimed is:

1           1. An etch/strip apparatus integrated with cleaning equipment,  
2   comprising:  
3           an etching line for etching and cleaning a substrate;  
4           a stripping line for stripping the substrate; and  
5           a cleaning line installed on the stripping line to clean and dry  
6   the substrate.

1           2. The apparatus as claimed in claim 1, further comprising:  
2           an elevator for conveying the substrate from the stripping line to  
3   the cleaning line.

1           3. The apparatus as claimed in claim 1, further comprising:  
2           a transfer for moving the substrate from the etching line to the  
3   stripping line.

1           4. The apparatus as claimed in claim 1, further comprising:  
2           a loader for feeding the substrate to the etching line; and  
3           a unloader for receiving the substrate from the cleaning line.

1           5. The apparatus as claimed in claim 1, wherein the etching line  
2   includes:  
3           an etch module for etching the substrate from the loader; and

4 a rinse module for cleaning the substrate fed from the etch  
5 module.

1 6. An integrated etch/strip/clean apparatus, comprising:  
2 an etching line for etching and cleaning a substrate;  
3 a stripping line for stripping said substrate; and  
4 a cleaning line integrated with said etching and stripping lines  
5 to clean and dry the substrate.

1 7. The apparatus of claim 6, wherein said cleaning line is  
2 installed on said stripping line.

1 8. The apparatus of claim 6, wherein said etching line includes:  
2 an etch module; and  
3 a rinse module connected to said etch module.

1 9. The apparatus of claim 6, further comprising:  
2 a transfer module to transfer said substrate from said etching  
3 line to said stripping line.

1 10. The apparatus of claim 9, wherein said transfer module  
2 includes:  
3 a pipe shower.

1 11. The apparatus of claim 6, further comprising:  
2 an elevator to transfer said substrate from said stripping line to  
3 said cleaning line.

1 12. The apparatus of claim 6, further comprising:  
2 a loader for loading the substrate to the etching line; and  
3 a unloader for unloading the substrate from the cleaning line.

1 13. The apparatus of claim 12, wherein said loader includes at  
2 least one of a conveyor and a robot.

1 14. The apparatus of claim 12, wherein said unloader includes  
2 at least one of a conveyor and a robot.